

Other Tools

[PT72 baselines](#)

SOURCE: Abdurrahman Gumus (CNF Fellows)

ADDED: 10/9/13

[Oxford 100, Trion, and UN770 baselines](#)

SOURCE: Tiffany Cheng (AFS:Fellows)

DATE: 2009-2011, depending on the tool.

For the Oxford 81 and 82 and the PT72, use the newer baselines available directly from the wiki.

[RIE etching PDMS](#)

SOURCE: Beth Rhoades

ADDED: 12/16/13

[Primaxx Vapor HF Etcher operating guide](#)

SOURCE: AFS

DATE: 2/18/13

Etching Monolayer Graphene

TOOL: YES asher

SOURCE: Melina Blees (McEuen Group)

ADDED: 2/17/13

50sccm O₂, 150W, 45s

Process temp: room temperature

Oxygen Etching of Parylene C Films

TOOL: PT 72

SOURCE: Ryan Badman (CNF Fellow)

ADDED: 2/2/15

O₂ clean recipe etches parylene C at 150 nm/min